

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Luo *et al.*

Appl. No.: 10/679,324

Filed: October 7, 2003

For: **Method and System for Active
Purging of Pellicle Volumes**

Confirmation No.: 2673

Art Unit: 3746

Examiner: *To Be Assigned*

Atty. Docket: 1857.2110000

Supplemental Information Disclosure Statement

Mail Stop Amendment

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

Listed on the accompanying IDS Forms are documents that may be considered material to the examination of this application, in compliance with the duty of disclosure requirements of 37 C.F.R. §§ 1.56, 1.97 and 1.98.

Applicants have listed publication dates on the attached IDS Forms based on information presently available to the undersigned. However, the listed publication dates should not be construed as an admission that the information was actually published on the dates indicated.

Applicants reserve the right to establish the patentability of the claimed invention over any of the information provided herewith, and/or to prove that this information may not be prior art, and/or to prove that this information may not be enabling for the teachings purportedly offered.

This statement should not be construed as a representation that a search has been made, or that information more material to the examination of the present patent

application does not exist. The Examiner is specifically requested not to rely solely on the material submitted herewith.

This Information Disclosure Statement is being filed under 37 C.F.R. § 1.97(b) before the mailing date of a first Office Action on the merits. No statement or fee is required.

Documents FP1 and FP2 were cited by a foreign patent office in a counterpart foreign application. A concise explanation of the relevance of the non-English language documents appears below in accordance with 37 C.F.R. § 1.98(a)(3):

Document FP1 (JP 2003-167328 A) appears to describe a device to minimize the deformation and the like of a pellicle frame when an inert gas supply part is put close to the pellicle frame to supply an inert gas into a pellicle space, as indicated by the English abstract submitted as Document NPL1.

Document FP2 (JP 2001-345264 A) appears to describe an aligner, an exposure method, and a manufacturing method of a device that can efficiently and stably reduce an absorption substance from space that is formed by a protection member in a mask, as indicated by the English abstract submitted as Document NPL2.

Copies of documents FP1, FP2, NPL1, and NPL2 are submitted. However, in accordance with 37 C.F.R. § 1.98(a)(2), no copy of the cited U.S. patent is submitted.

It is respectfully requested that the Examiner initial and return copies of the enclosed IDS Forms, and indicate in the official file wrapper of this patent application that the documents have been considered.

The U.S. Patent and Trademark Office is hereby authorized to charge any fee deficiency, or credit any overpayment, to our Deposit Account No. 19-0036.

Respectfully submitted,

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